

| | Hits | Search Text | DBs |
|----|-------|--|--|
| 1 | 270 | (silane sih4 ("SiH.sub.4")) with ("nitrous oxide" n2o("N.sub.2O")) with (nitrogen n2 ("N.sub.2")) with (NH3 ("NH.sub.3")) | US-PGPUB; USPAT; USOCR |
| 2 | 142 | S62 and S79 | US-PGPUB; USPAT; USOCR |
| 3 | 7 | ("20010044220" "4543707" "5880018" "6060132" "6153541" "6221794" "6294460").PN. OR ("6410461").URPN. | US-PGPUB; USPAT; USOCR |
| 4 | 1 | ("2001/0044220").URPN. | USPAT |
| 5 | 71 | S74 and "240" and degrees | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 6 | 1 | S74 and "240" adj degrees | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 7 | 27748 | Sion (silicon adj oxynitride) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 8 | 1378 | S65 same S68 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 9 | 1771 | (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and magnet and coil | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 10 | 0 | ("2005/0088261").URPN. | USPAT |
| 11 | 1 | (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and S70 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 12 | 230 | S69 with S65 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 13 | 1 | S70 and cantilever | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |

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| 14 | 14288 | silicon adj oxynitride | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 15 | 4544 | S62 with dielectric | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 16 | 381 | S63 same S65 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 17 | 5471 | S68 with dielectric | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 18 | 17636 | pecvd ("plasma enhanced chemical vapor deposition") | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 19 | 1282 | S63 and S65 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 20 | 264 | (335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 21 | 129 | S63 and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 22 | 2 | ("6768403").PN. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 23 | 119 | (335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and cantilever and dielectric | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |

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| 24 | 60 | (335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro- electromechanical or micro-electro- mechanical or mems or microactuator) and substrate and S58 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 25 | 169 | (335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro- electromechanical or micro-electro- mechanical or mems or microactuator) and dielectric and substrate | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 26 | 138005 | dielectric same (silicon oxygen nitrogen si o n) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 27 | 96276 | dielectric with (silicon oxygen nitrogen si o n) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 28 | 105 | (335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro- electromechanical or micro-electro- mechanical or mems or microactuator) and magnet\$3 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 29 | 174 | (335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro- electromechanical or micro-electro- mechanical or mems or microactuator) and dielectric | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 30 | 935 | 335/78.ccls. 200/181.ccls. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |
| 31 | 26 | 333/101.ccls. and (microelectromechanical or micro- electromechanical or micro-electro- mechanical or mems or microactuator) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB |